



Form PTO-1449

INFORMATION DISCLOSURE CITATION
IN AN APPLICATION

(Use several sheets if necessary)

Docket Number 325772020700

Application Number 09/735,608

Hiroshi Hatno

Filing Date: December 14, 2000

Group Art Unit 2653

Examiner Kim Kwok Chu

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U.S. PATENT DOCUMENTS

Technology Center 2600

Examiner Initials	Ref. No.	Date	Document No.	Name	Class	Subclass	Filing Date If Appropriate
lc		06-12-1945	2,378,301	Edward K Kaprellan	359	731	04-08-1944
lc		10-16-1962	3,059,113	T.F. McHenry	250	353	05-25-1960
lc		10-24-1978	4,121,890	Braun	356	4.02	08-17-1977
lc		01-02-2001	6,169,637	Tsunashima	359	726	05-04-1999
lc		03-20-1984	4,437,746	Ikemori	369	272	03-25-1982

FOREIGN PATENT DOCUMENTS

Examiner Initials	Ref. No.	Date	Document No.	Country	Class	Subclass	Translation YES NO

OTHER DOCUMENTS

(including author, title, Date, Pertinent Pages, Etc.)

Examiner Initials	Ref. No.	Title
lc		REFLECTING MICROOPTICAL SYSTEM, filed November 25, 1999 as U.S. Serial No.: 09/450,271

EXAMINER: Kim Chu

DATE CONSIDERED: 5/11/05

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